



# **ECE695A: Reliability Physics of Nano-Transistors**

## **Lecture 6: Defects in the Bulk and at Interfaces**

Muhammad Ashraful Alam  
[alam@purdue.edu](mailto:alam@purdue.edu)

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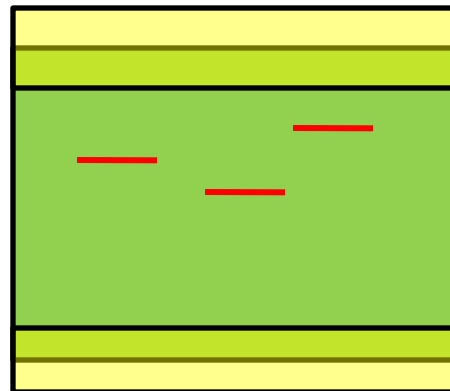
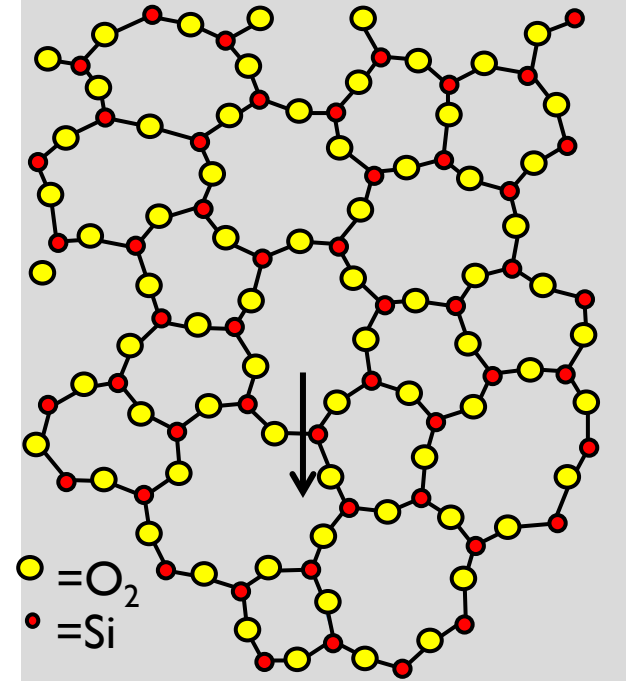
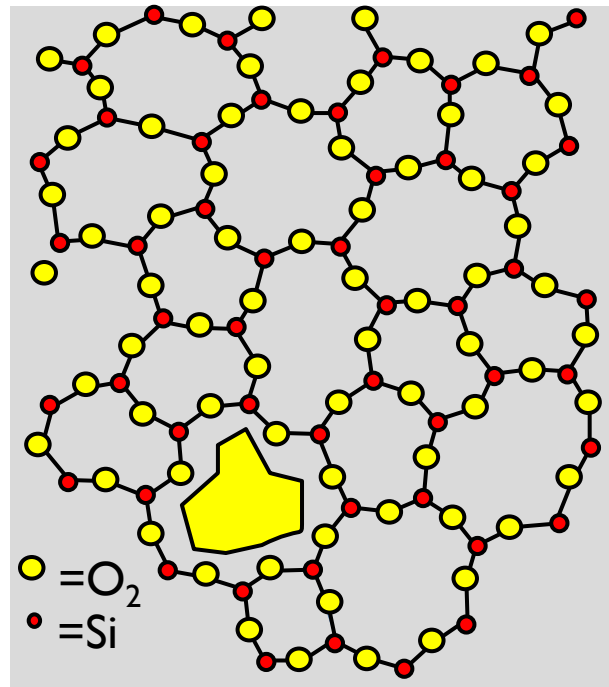
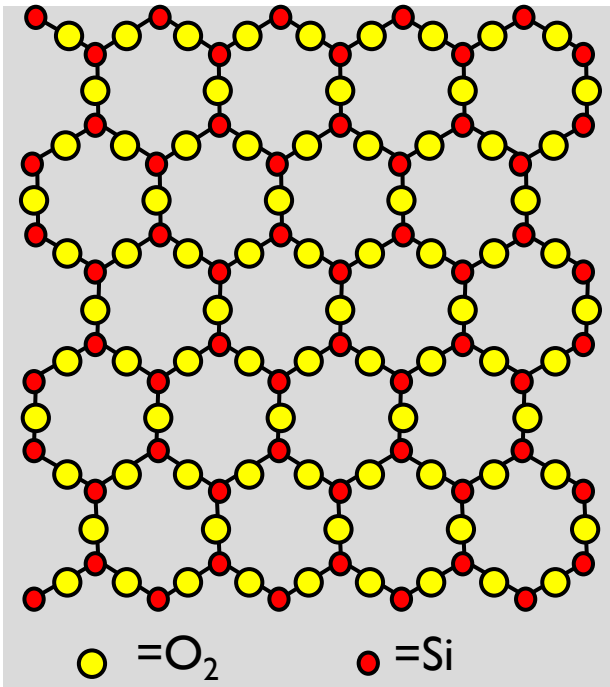
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# Outline of lecture 6

1. Strain in materials/origin of defects
2. Examples: bulk defects
3. Examples: interface defects
4. Measurements
5. Conclusions

# Meaning of an oxide/nitride defect

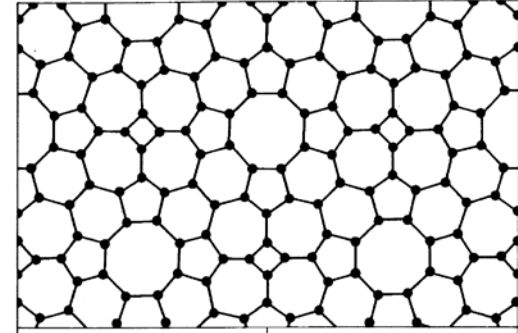


# Origin of defects and Maxwell constraints

Dimensionality      Points to be stabilized

$$M_0 = DN - N_c - (D + \alpha)$$

↓
↙
↖
Constraints



$$N \equiv \sum_{r=1}^k n_r$$

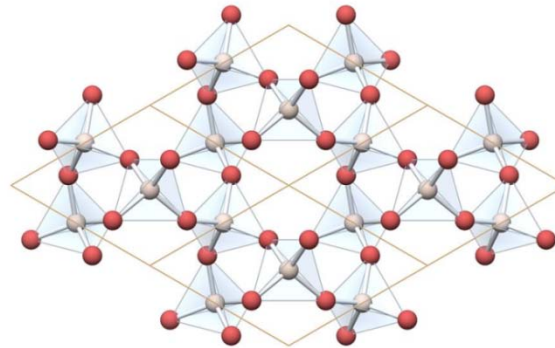
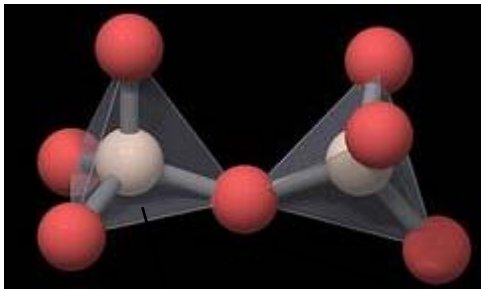
←
←
Types of atoms with different coordination  
←
Number of atoms with coordination r

$$N_c \equiv \left[ \sum_{r=1}^k n_r \frac{r}{2} \right]_{bond} + \left[ \sum_{r=1}^k n_r \frac{(D-1)}{2} (2r - D) \right]_{angle}$$

$M_0 > 0$  unstable,  $M_0 < 0$  stable

# Example 4: 3D constraints for binary solids

$$N_c \equiv \left[ \sum_{r=1}^k n_r \frac{r}{2} \right]_{bond} + \left[ \sum_{r=1}^k n_r \frac{(D-1)}{2} (2r - D) \right]_{angle}$$



J.C. Phillips, 1979.  
Thorpe, 1982.

$$N_c(Si) = \left[ \frac{\langle N_{c,1} \rangle}{2} \right]_{r_{ij}} + \left( 2 \langle N_{c,1} \rangle - 3 \right) \Big]_{\theta_{ijk}}$$

$$N_c(O) = \left[ \frac{\langle N_{c,2} \rangle}{2} \right] + 0$$

Average Si coordination ...  $\langle N_{c,1} \rangle$  Average O coordination ...  $\langle N_{c,2} \rangle$

$$\text{Average coordination ... } \langle N_c^{A_x B_{1-x}} \rangle = x \langle N_c^A \rangle + (1-x) \langle N_c^B \rangle$$

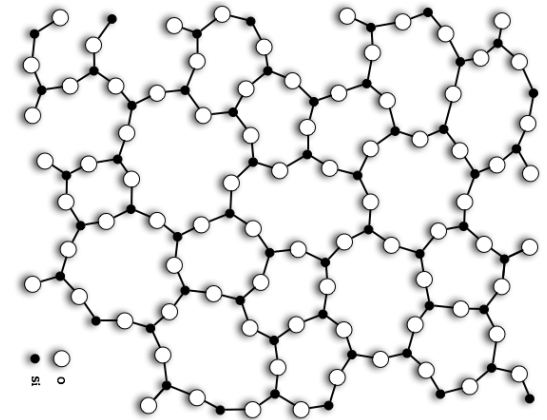
# Example 4: at what value of x is SiO strain-free?

$$\frac{M_0}{N} \approx 3 - x \left[ \frac{\langle N_c^{Si} \rangle}{2} + (2\langle N_c^{Si} \rangle - 3) \right] - (1-x) \left[ \frac{\langle N_c^O \rangle}{2} + 0 \right]$$

$$= 3 - x \left[ \frac{4}{2} + (2 \times 4 - 3) \right] - (1-x) \times \frac{2}{2}$$

$$0 \Rightarrow 7x + (1-x) = 3 \quad x = \frac{1}{3}$$

$Si_{1/3}O_{1-1/3} = SiO_2$  stress - free optimally coordinated!



$$\langle N_c^{SiO_2} \rangle = 0.33 * \langle N_c^{Si} \rangle + 0.66 * \langle N_c^O \rangle$$

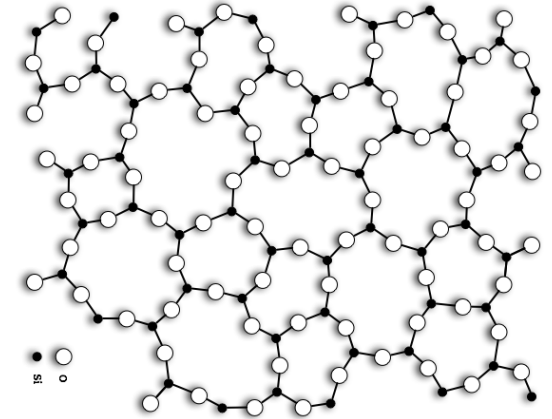
$$= 2.64$$

A very important number that arises in all good 3D 'glass formers'

## Example 2: Is $\text{Si}_3\text{N}_4$ optimally coordinated?

$$\begin{aligned}\frac{M_0}{N} &\approx 3 - x \left[ \frac{\langle N_c^{\text{Si}} \rangle}{2} + (2\langle N_c^{\text{Si}} \rangle - 3) \right] - (1-x) \left[ \frac{\langle N_c^{\text{O}} \rangle}{2} + 0 \right] \\ &= 3 - \left\{ \frac{3}{(3+4)} \left[ \frac{4}{2} + (2 \times 4 - 3) \right] + \frac{4}{(4+3)} \times \frac{3}{2} \right\} \\ &= -0.8571\end{aligned}$$

*J.C. Phillips, 1979.  
Thorpe, 1982.*



Silicon nitride is over coordinated,  
therefore prone to defect formation

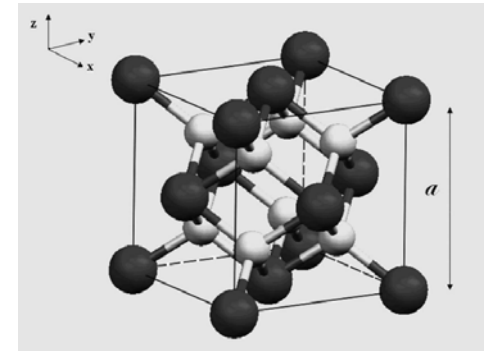
$$\text{Average coordination ..... } \langle N_c^{\text{Si}_3\text{N}_4} \rangle = \frac{3}{7} \langle N_c^{\text{Si}} \rangle + \frac{4}{7} \langle N_c^{\text{N}} \rangle = \frac{24}{7} = 3.42$$

$$\text{Probability of defect formation: } D \propto (\Delta\theta)^2 \sim (N_c - N_c^*)^2$$



# Example: what about HfO<sub>2</sub>?

$$\begin{aligned}\frac{M_0}{N} &\approx 3 - x \left[ \frac{\langle N_c^{Hf} \rangle}{2} + (2\langle N_c^{Hf} \rangle - 3) \right] - (1-x) \left[ \frac{\langle N_c^O \rangle}{2} + 0 \right] \\ &= 3 - \left\{ \frac{1}{(1+2)} \left[ \frac{8}{2} + (2 \times 8 - 3) \right] + \frac{2}{(1+2)} \times \frac{4}{2} \right\} \\ &= -4\end{aligned}$$



HfO<sub>2</sub> is over coordinated, therefore prone to defect formation

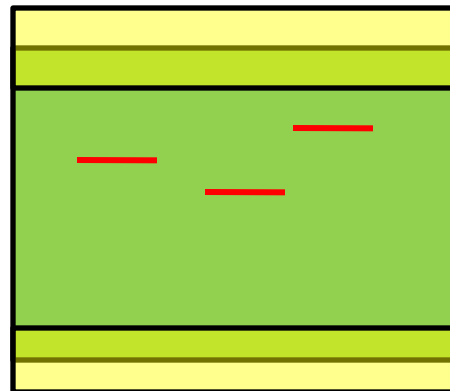
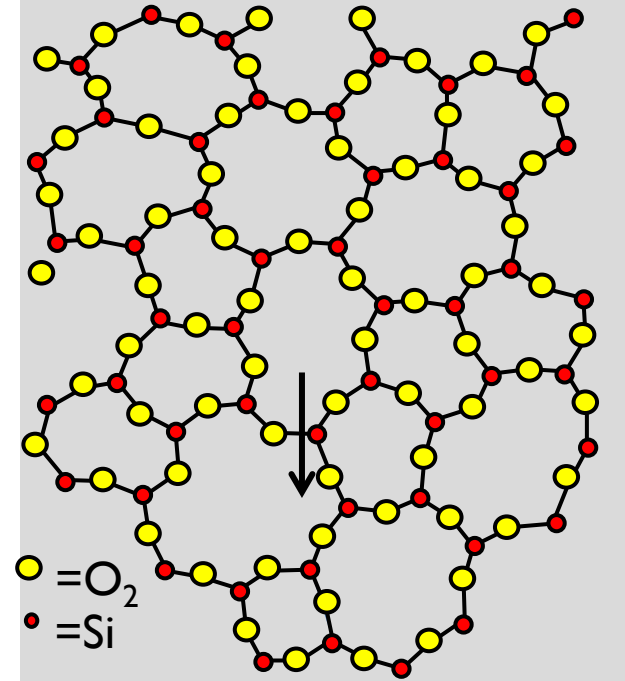
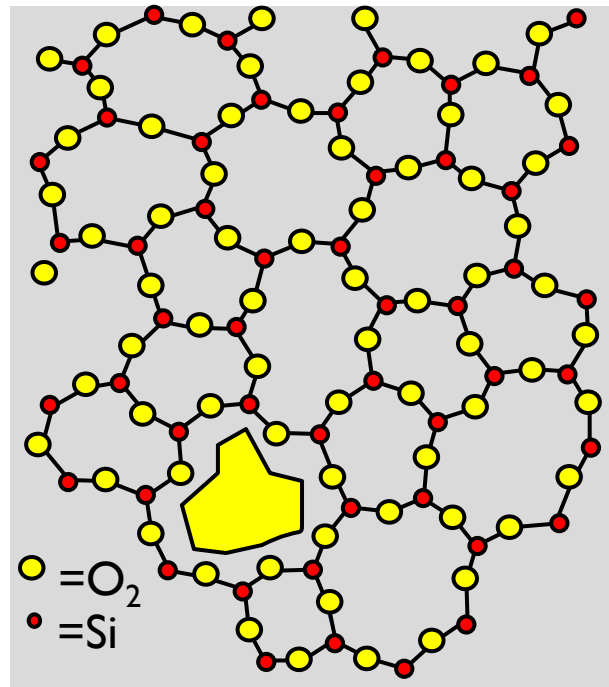
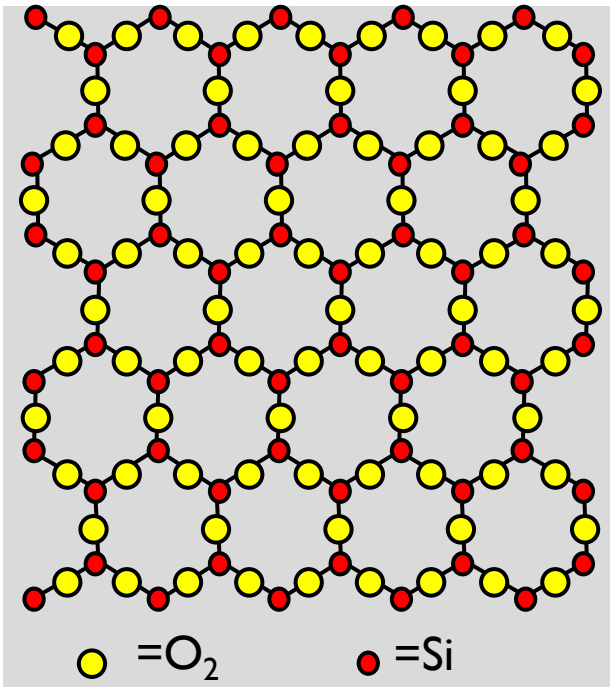
Average coordination .....  $\langle N_c^{HfO_2} \rangle = \frac{1}{3} \langle N_c^{Hf} \rangle + \frac{2}{3} \langle N_c^O \rangle = \frac{16}{3} = 5.33$

Probability of defect formation:  $N_{\text{Defects}} \sim (N_c - N_c^*)^2$

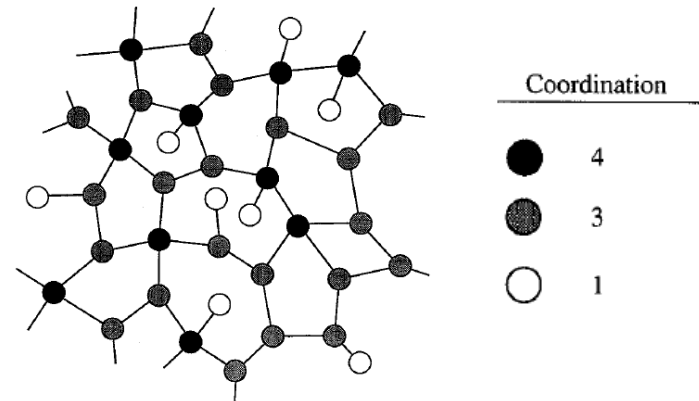
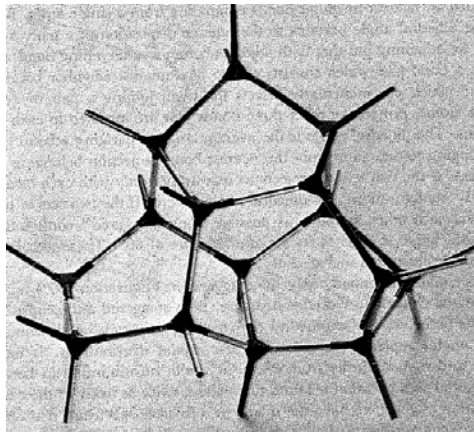
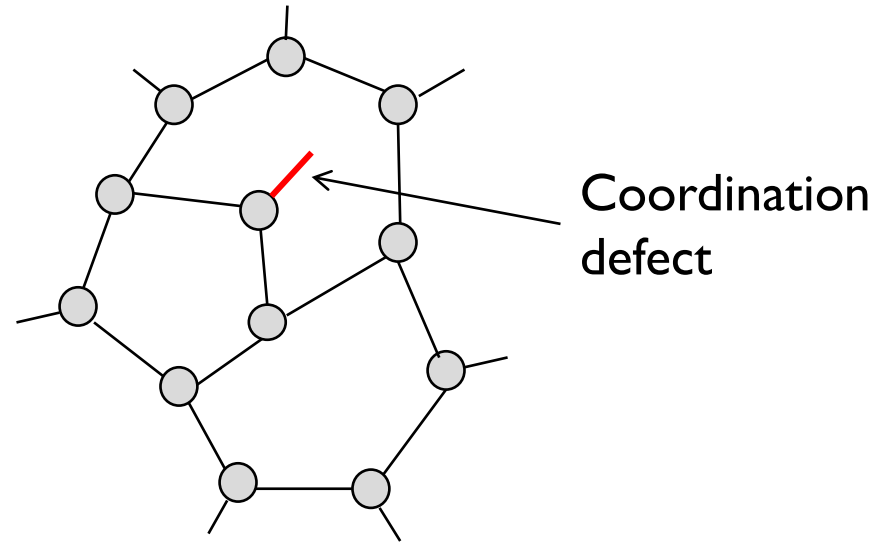
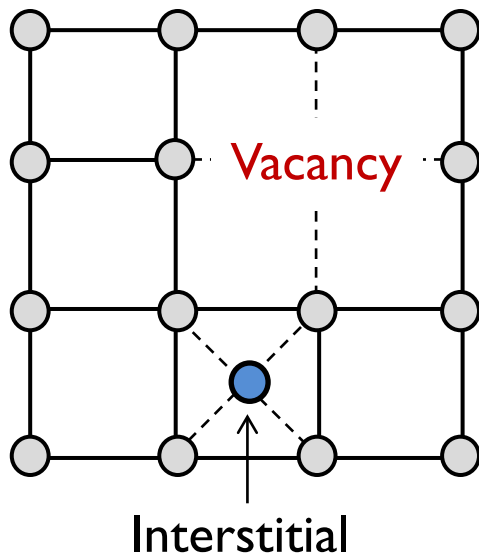
# Outline

1. Strain in materials/origin of defects
2. Examples: bulk defects
3. Examples: interface defects
4. Measurements
5. Conclusions

# Meaning of an oxide/nitride defect



# Defects in a-Si (coordination defects)



Far fewer **types** of defects compared to crystalline materials ...

# Examples: a-Si vs. a-Si:H

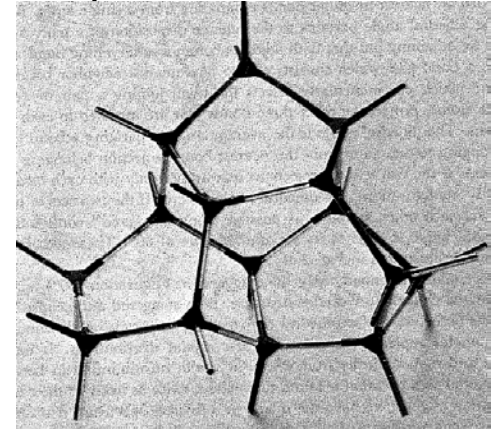
Ex. Is a-Si optimally coordinated?

$$\frac{M_0}{N} \approx 3 - \left[ \frac{\langle N_c^{Si} \rangle}{2} + (2\langle N_c^{Si} \rangle - 3) \right]$$

$$= 3 - \left\{ \frac{4}{2} + (2 \times 4 - 3) \right\} = -4.$$

A-Si is highly overcoordinated, prone to defect formation

R.C. Street, *Hydrogenated a-Si*, p. 39.



Ex. At what value of x, is  $\text{Si}_x\text{H}_{1-x}$  optimally coordinated?

$$\frac{M_0}{N} \approx 3 - x \left[ \frac{\langle N_c^{Si} \rangle}{2} + (2\langle N_c^{Si} \rangle - 3) \right] + (1-x) \frac{\langle N_c^H \rangle}{2}$$

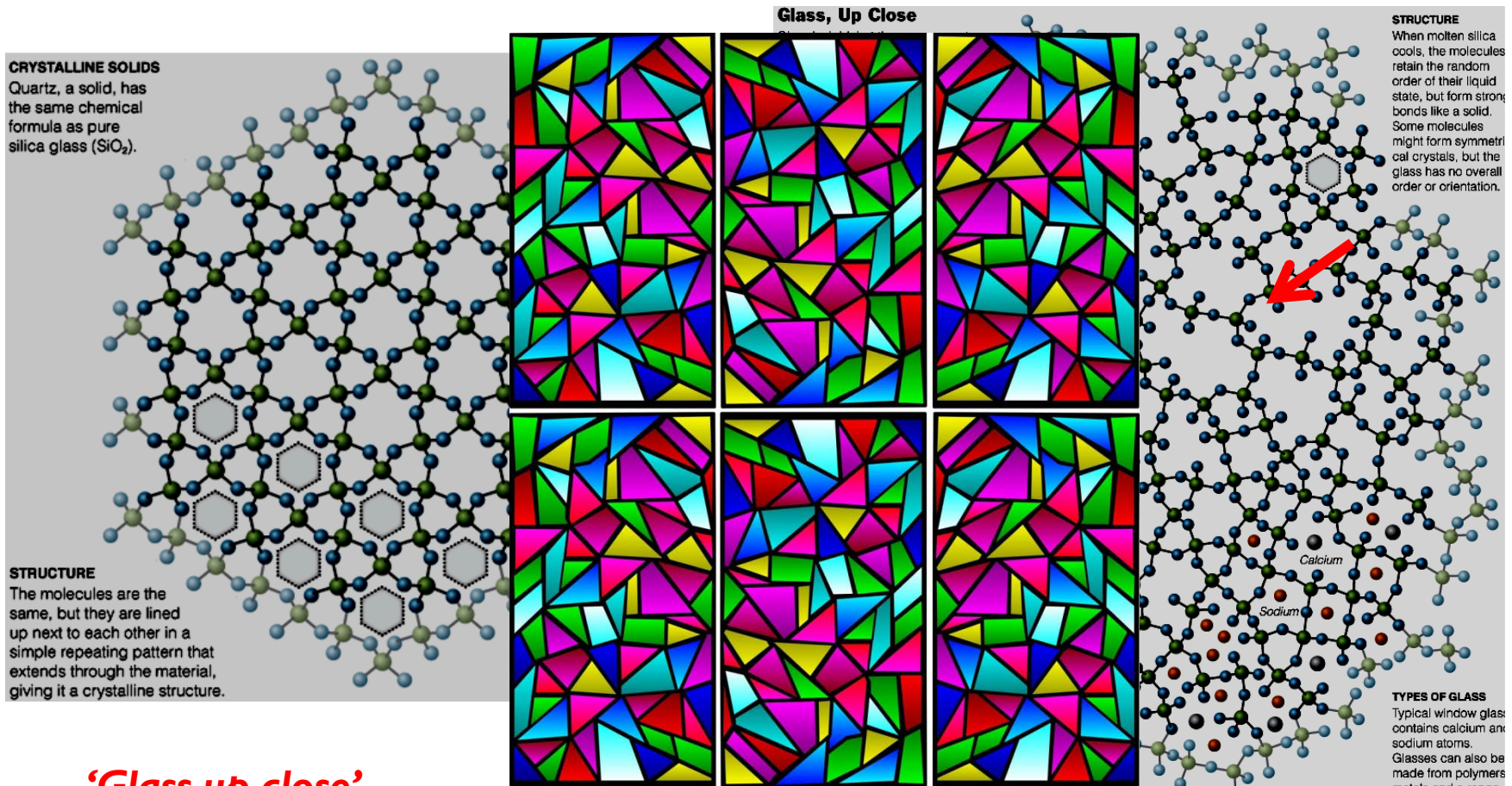
$$= 3 - x \left[ \frac{4}{2} + (2 \times 4 - 3) \right] + (1-x) \frac{1}{2}$$

$$0 \Rightarrow 7x + (1-x)/2 = 3 \quad x = \frac{2.5}{6.5} = 40\%$$

Typically 10% H

$$\langle N_c^{SiH} \rangle = 0.9 \langle N_c^{Si} \rangle + 0.1 \langle N_c^H \rangle = 3.7$$

# Crystalline vs. amorphous oxides

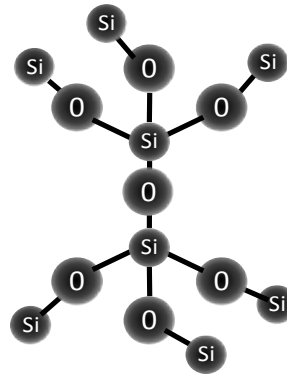
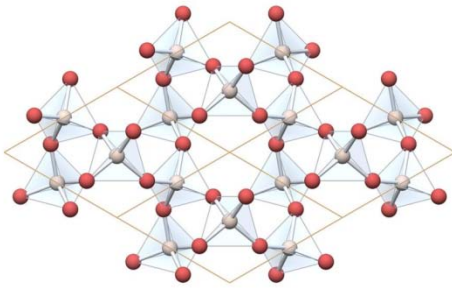


***'Glass up close',***  
*NY Times, July 29, 2008.*

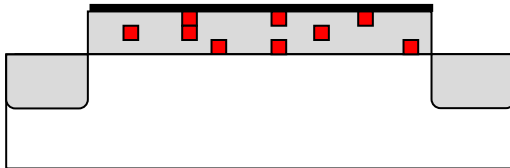
Purple: Nickel oxide  
Blue: Cobalt oxide  
Yellow/blue-green: Iron oxide  
Cherry Red: Gold oxide

# Bulk defects E' center

Courtesy:  
Prof. Lenahan



(a) Vacancy free SiO<sub>2</sub>

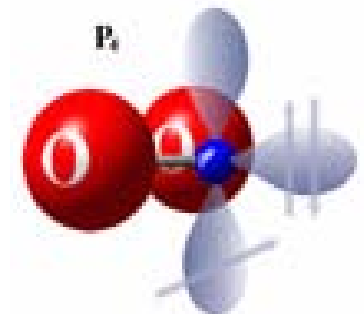
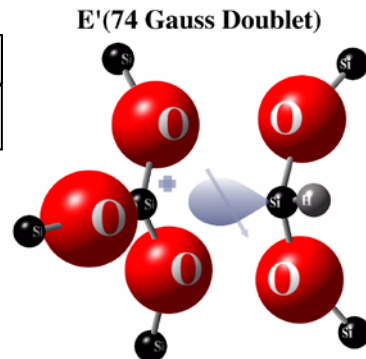
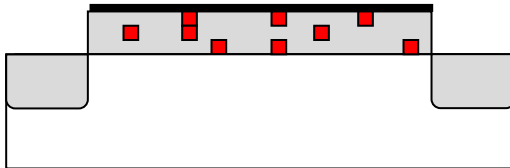
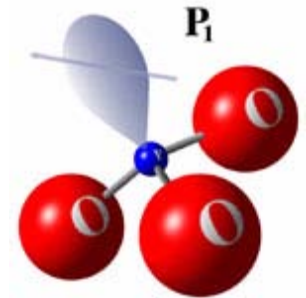
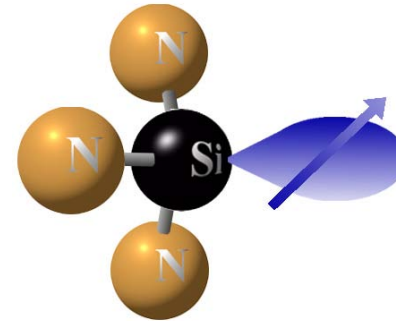
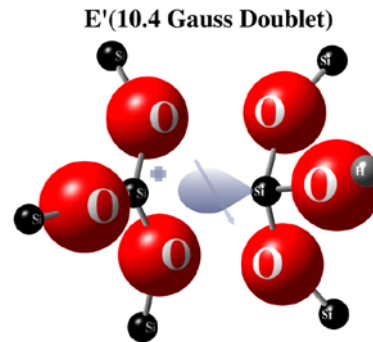
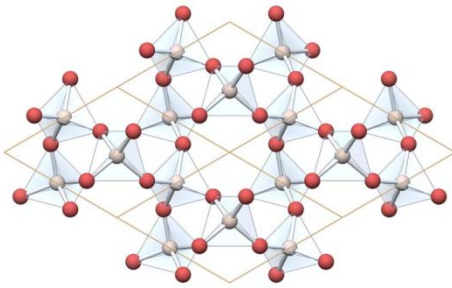


Responsible for gate dielectric breakdown as well as trapped charges



# Bulk defects of missing Oxygen: E', K, and P defects

Courtesy:  
Prof. Lenahan



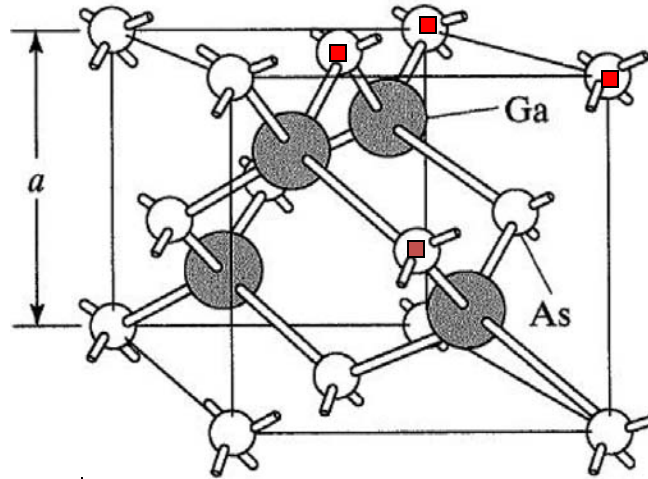
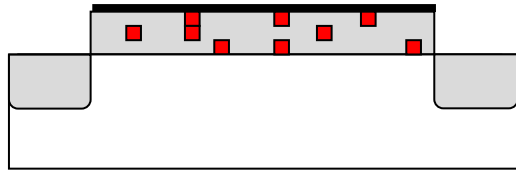
Responsible for gate dielectric breakdown



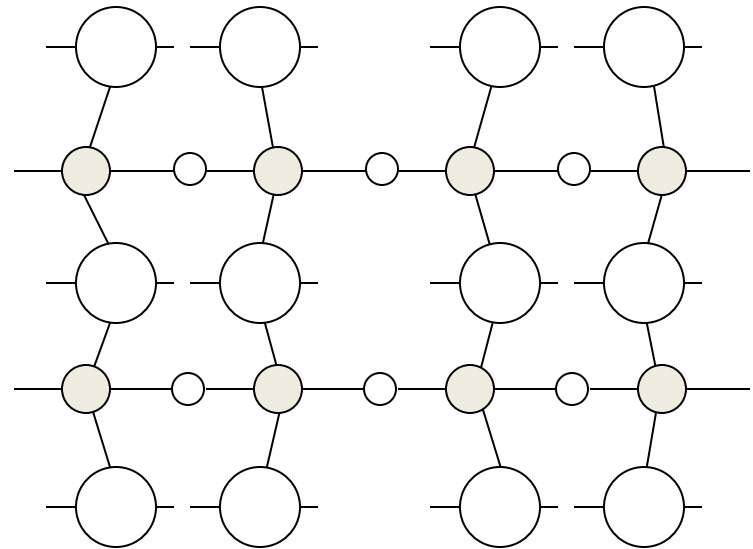
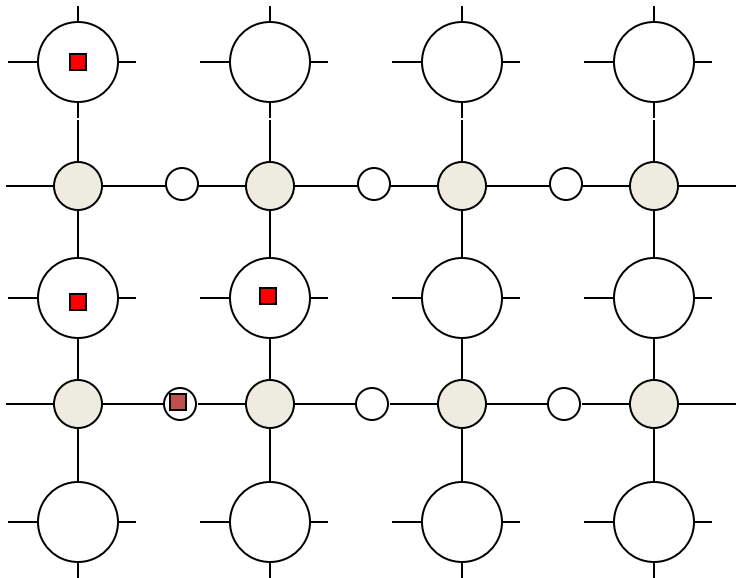
# Outline of lecture 6

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# Surface reconstruction

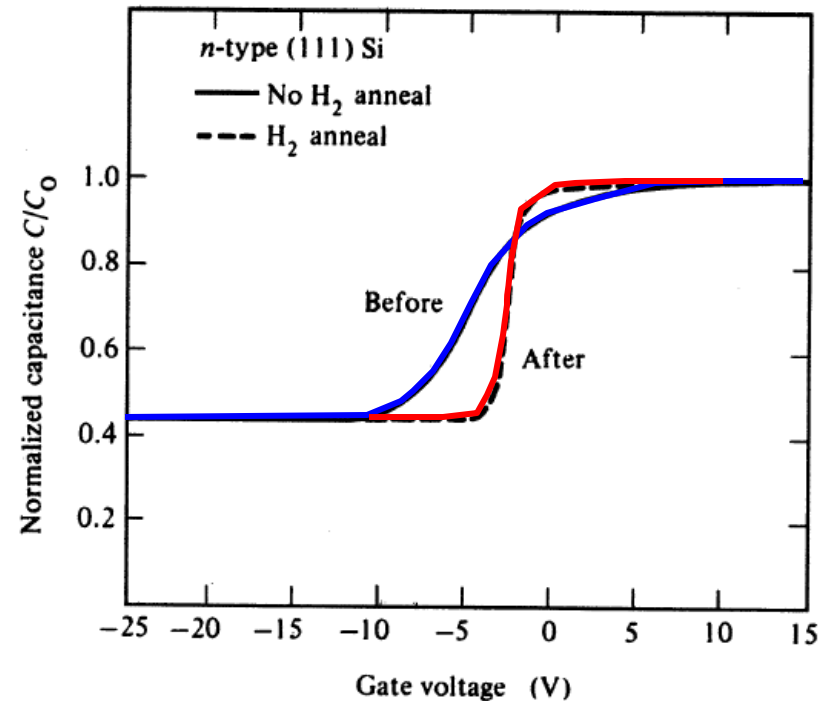
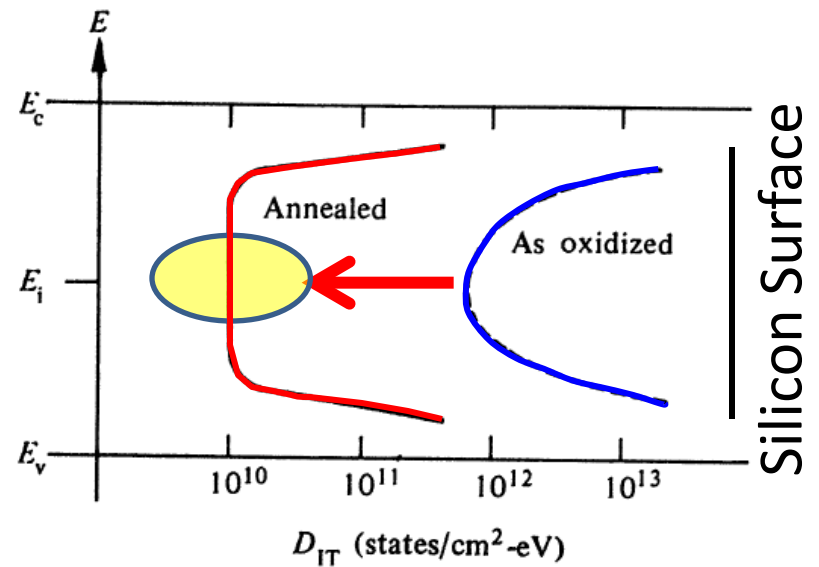
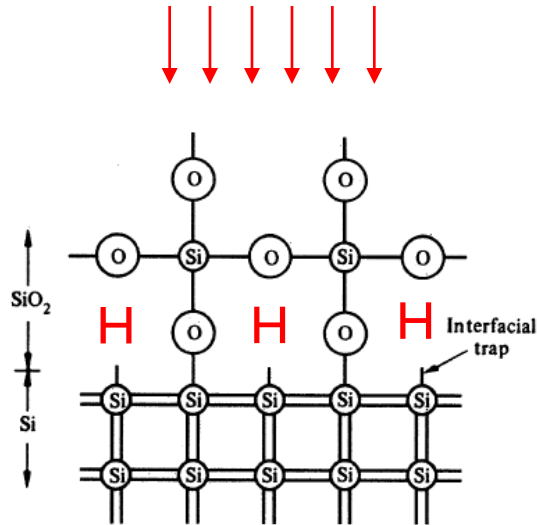


High defect density



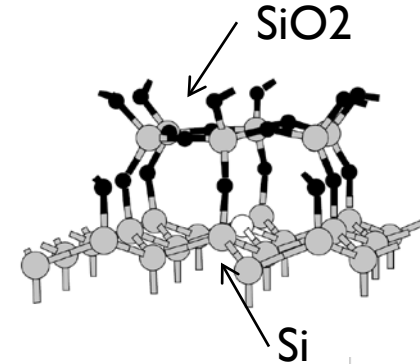
# C-V Stretchout, interface defects, and Andy Grove

## Forming gas anneal



# Example: Si/SiO<sub>2</sub> interface is strained

Consider 1 monolayer of Si/SiO<sub>2</sub> at the interface  
(0.5 monolayers of each: 0.5 atoms of Si/1.5 atoms of SiO<sub>2</sub>)



(1) Silicon is highly over-coordinated, because ...

$$Si \rightarrow 0.5 \times N_{Si} = 0.5 \times 4 = 2 \text{ bonds.}$$

$$\text{Average bonds} = 2 \text{ bonds}/0.5 = 4$$

(2) SiO<sub>2</sub> is optimally coordinated ...

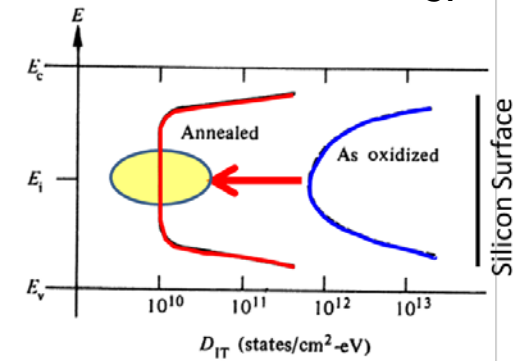
$$SiO_2 \rightarrow 1.5 \times (0.33 \times 4 + 0.66 \times 2) = 4 \text{ bonds.}$$

$$\text{Average bonds} \rightarrow 4 \text{ bonds}/1.5 \text{ atoms} = 2.66$$

(3) Si/SiO<sub>2</sub> is over-coordinated, so prone to defect formation ...

Average coordination at the interface

$$\rightarrow (4 + 2) \text{ bonds}/(1.5 \text{ atoms} + 0.5 \text{ atoms}) = 3.$$



# Hydrogenation improves Si/SiO<sub>2</sub> interface

Consider 1 monolayer of Si<sub>0.9</sub>H<sub>0.1</sub>/SiO<sub>2</sub> at the interface

(0.5 monolayers of each: 0.5+0.05 atoms of Si and H/1.5 atoms of SiO<sub>2</sub>)

(4) SiH/SiO<sub>2</sub> is relaxed, with reduced defect density

$$Si_{0.9}H_{0.1} \rightarrow 0.55 \times (0.9N_{Si} + 0.1N_H) = 2.03 \text{ bonds.}$$

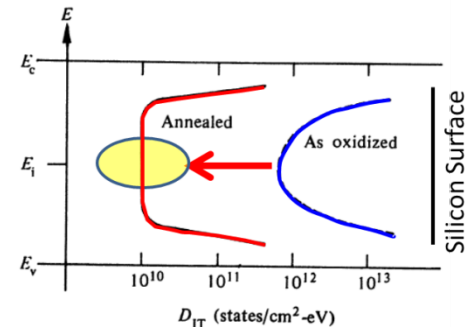
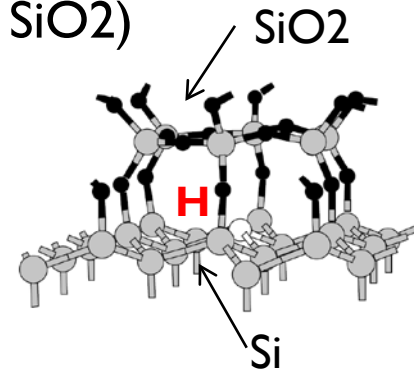
$$SiO_2 \rightarrow 1.5 \times (0.33 \times 4 + 0.66 \times 2) = 4 \text{ bonds.}$$

Average coordination

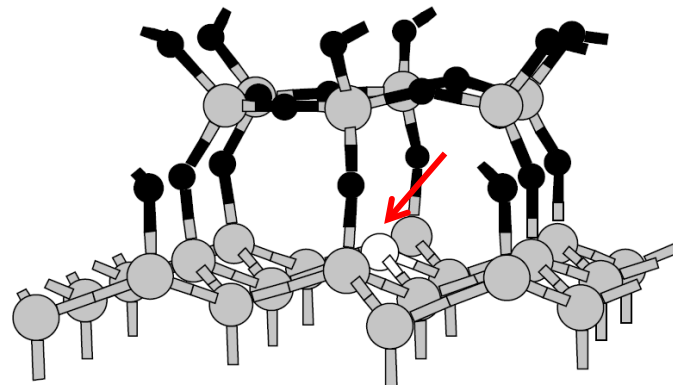
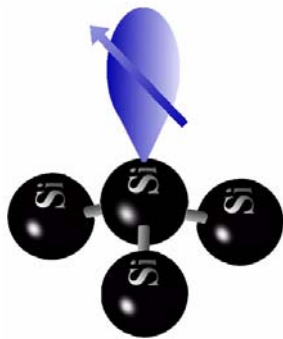
$$\rightarrow 6.03 \text{ bonds} / (1.5 \text{ atoms} + 0.55 \text{ atoms}) = 2.94$$

To conclude, defects at interface

$$SiO_2 < SiH-SiO_2 < Si-SiO_2 < Si$$

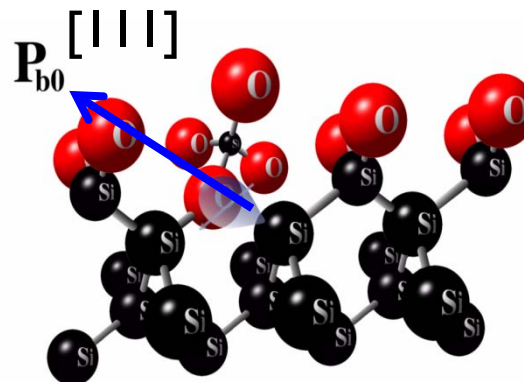
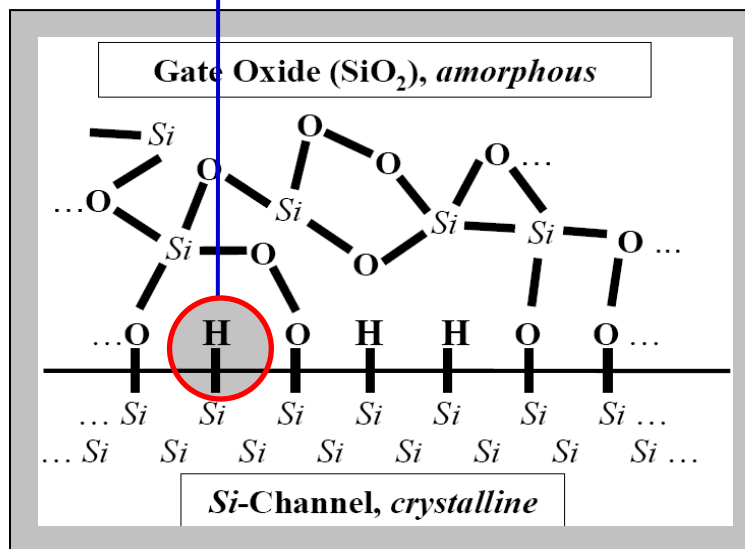


# Pb centers – interface traps

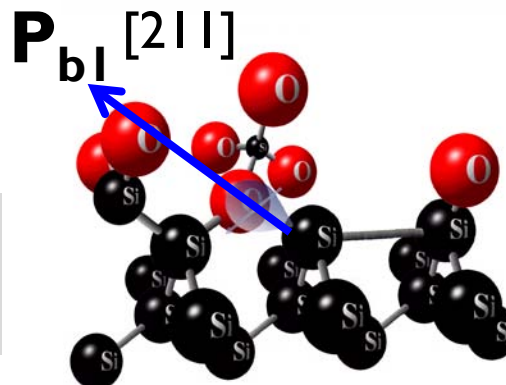


$[111]$  surface  
 $P_b$  along  $[111]$

*Stirling, PRL, 2000.*



$[100]$  surface  
 $P_{b0}$  along  $[111]$



$[100]$  surface  
 $P_{b1}$  along  $[211]$

Of  $P_a$ ,  $P_b$ ,  $P_c$  -- only  $P_b$  survives  
Related to NBTI degradation

# Outline

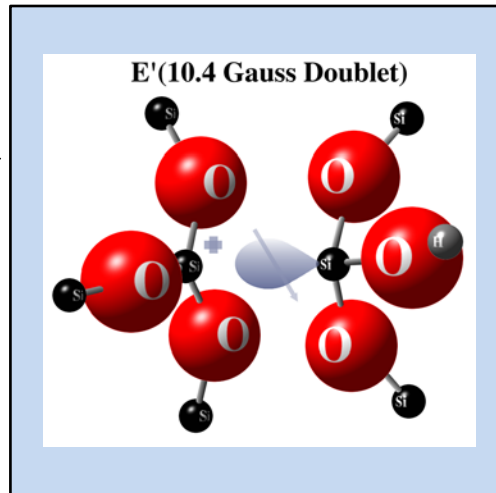
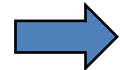
1. Strain in materials/origin of defects
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# Electron spin resonance: a 'microscope' for defects

10 GHz Microwave

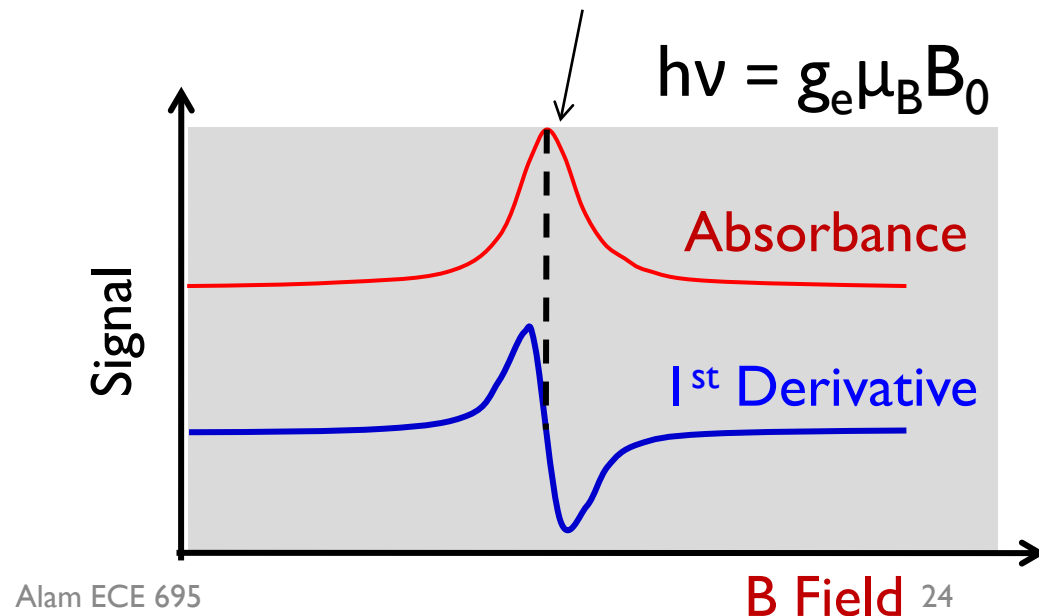
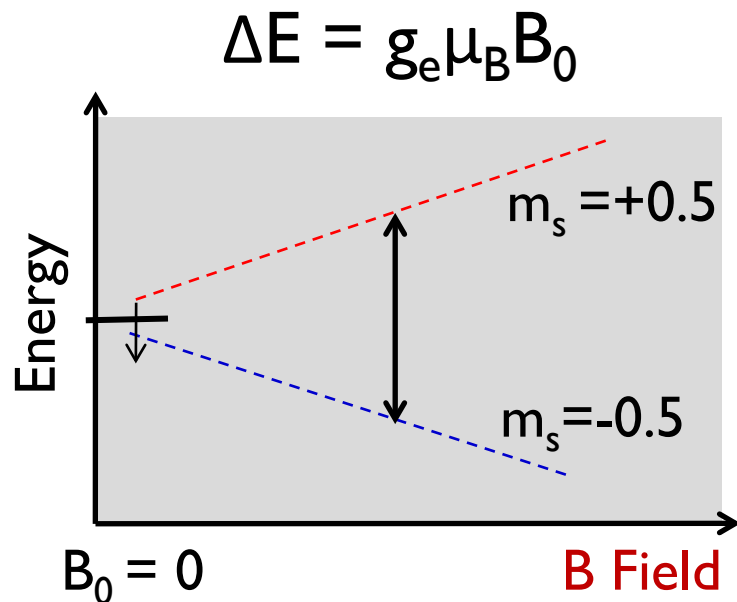


Variable B-field



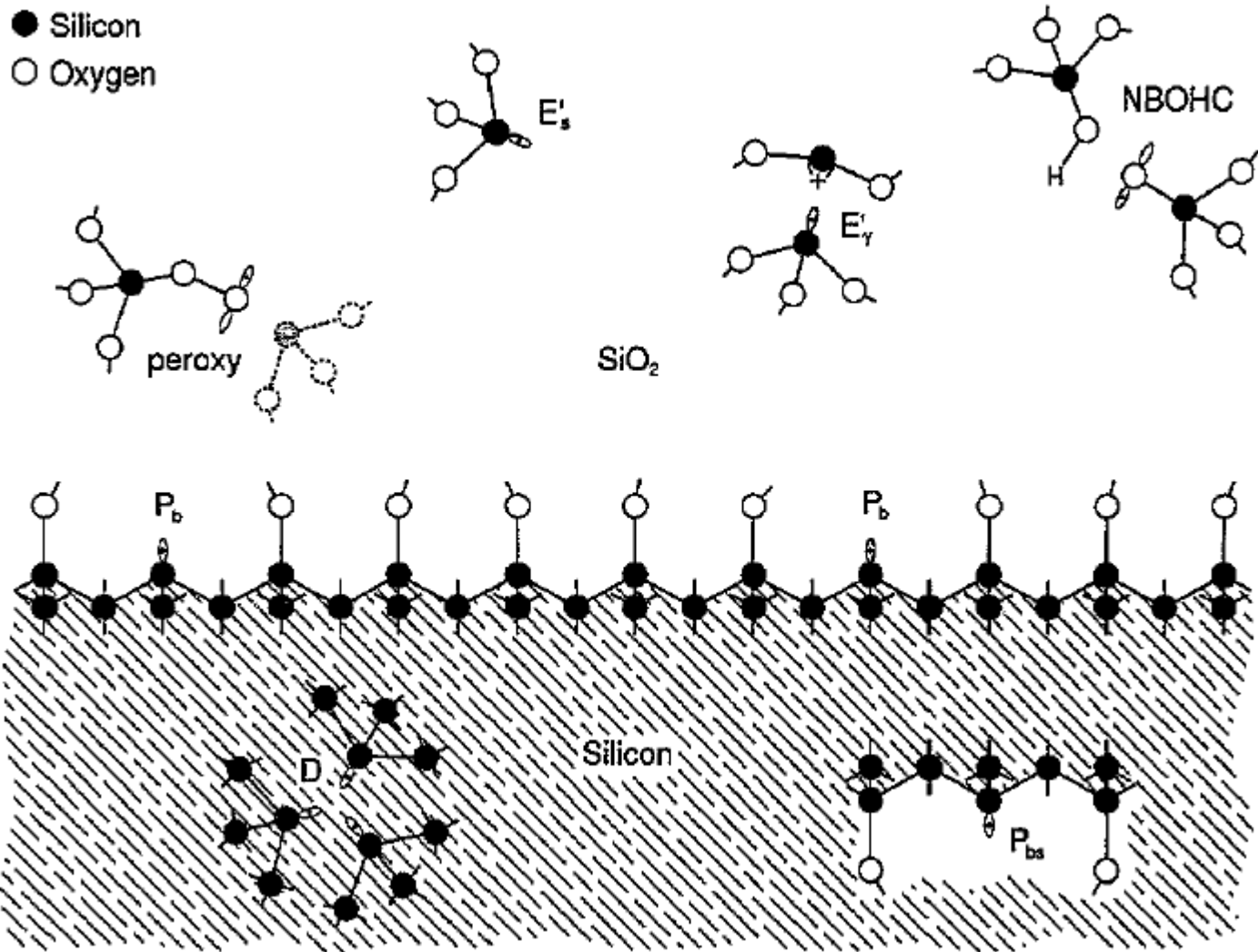
Absorption spectra

B-value suggests  
local environment





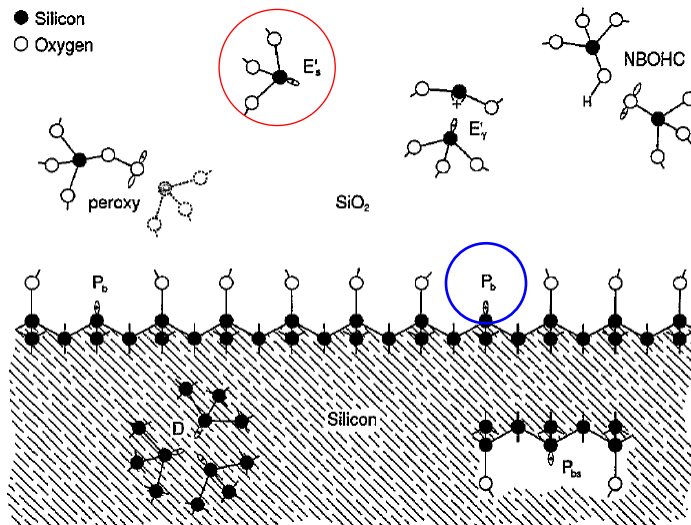
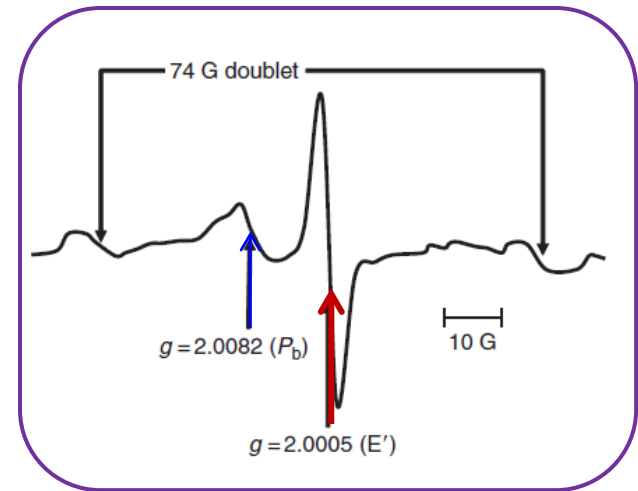
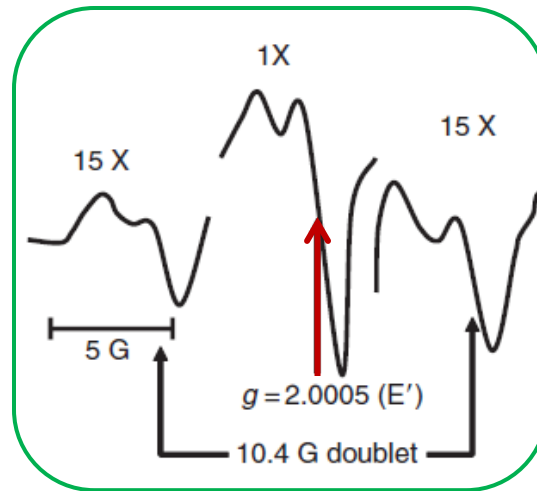
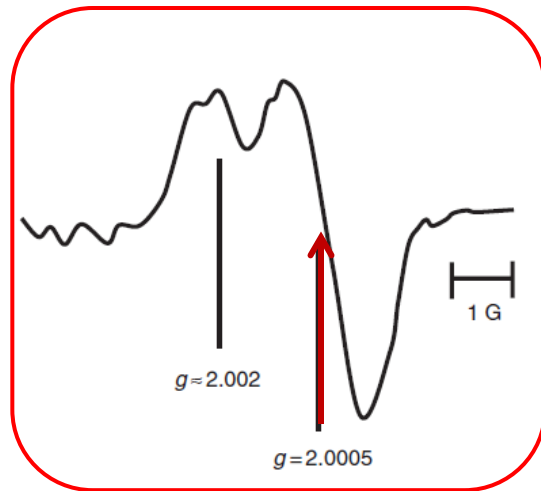
# Different types of ESR-visible defects



Nonbridging oxygen hole center

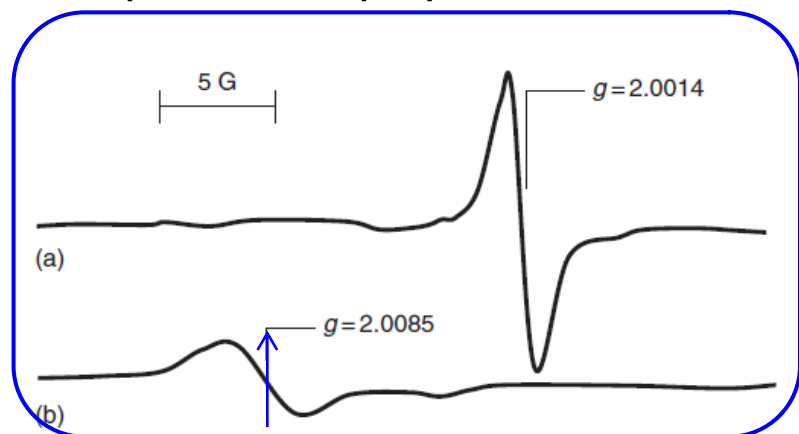
*Helms and Poindexter, 1994.*

# ESR signature of different defects

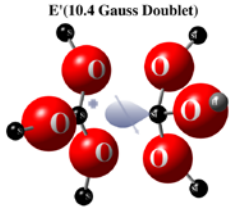


P. M. Lenahan, 2004.

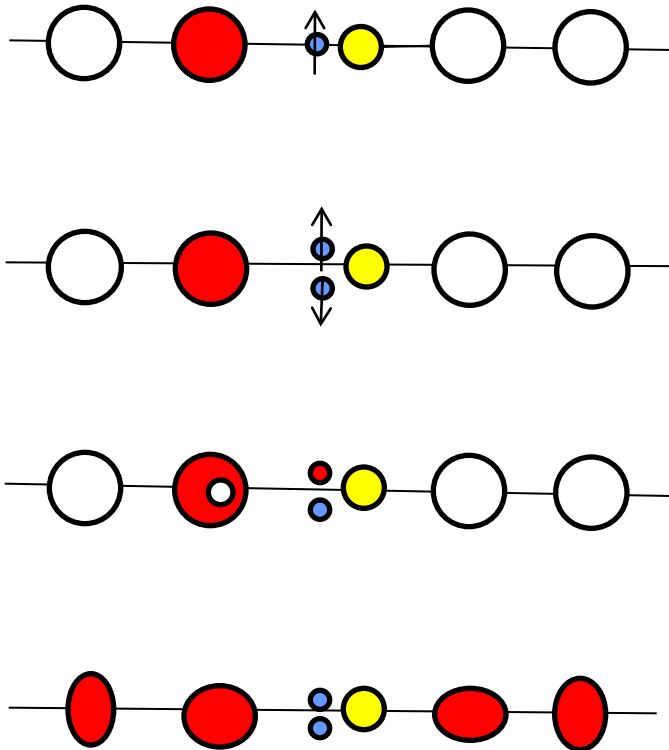
Pb parallel and perpendicular to  $\langle 111 \rangle$



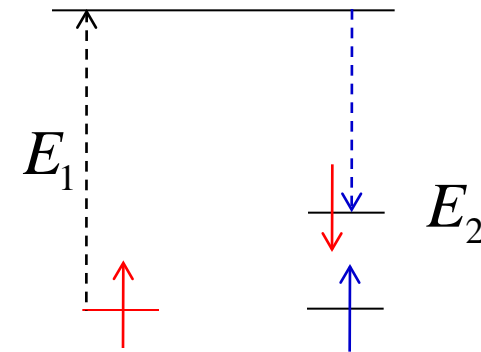
# ESR invisible defects (negative U traps)



Paramagnetic materials may appear diamagnetic



$$D_0 + E_1 = D^+ \quad D_0 - E_2 = D^-$$



$$2D_0 + (E_1 - E_2) = D^+ + D^-$$

$$2D_0 + (E_1 - E_2) - U_{e-h} = D^+ + D^-$$

Like superconductivity with phonon assisted e-e attraction

# Conclusions

- ❑ Maxwell relationship anticipates bulk and interface defects as a consequence of excessive coordination. In  $\text{SiO}_2$ , bulk defects are called E' centers and at the  $\text{Si}/\text{SiO}_2$  interface, interface defects are called Pb centers.
- ❑ The theory also explains how small atoms like H relaxes the structure and reduces defect density.
- ❑ Determining the precise number of angle constraints is sometime difficult. If the angle are very floppy, we assign the constraint to zero as an initial guess.
- ❑ Electron spin resonance (ESR) techniques are often used to determine types of defects in a systems. There are ESR-invisible many body defects that can be detected by other methods.

# References

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- First-Principles Investigations of Low Energy E' center Precursors in Amorphous Silica, PRL, 106, 206402, 2011 provides a sophisticated MD-DFT perspective of these defects. Another review by J. Robertson, “Interfaces and defects of high-K oxides on Silicon, Solid State Electronics, 49, 283, 2005.

# Review questions

G1: Why do we not account for angle constraint in for oxygen in  $\text{SiO}_2$ ?

G2: Explain why amorphous structures actually have fewer types of defects

G3: If you needed to calculate  $\text{HfO}_2/\text{SiO}_2$  interface properties – How many monolayers of atoms should you consider in  $\text{HfO}_2$  side?

G4: What is the difference between a Pb center and E' center?

G5: Support the statement that “Hydrogen incorporation in c-Si makes the structure amorphous”.

G6: 10.4 GHz doublets and 74GHz doublet indicates the backbonding of which atom?

G7: Name a technique other than ESR that might be used to characterize defects?

G8: Why is negative U traps invisible to ESR?